

[Broad Band Monitoring]

The precise production of coating systems with complicated designs has developed to one of the major challenges in modern optical thin film technology.

Besides extended investigations in the stability and reproducibility of deposition techniques, a variety of approaches to control the growing layers has been studied on the way towards the targeted ideal process concept which would allow the realization of even extremely complicated coating designs in a linear chain without iteration steps.

Even though this ultimate production technique could not be achieved completely until now, the related research work of the last two decades has furnished enormous progress, especially in the field of online-monitoring in deposition processes.

The present workshop is dedicated to a comprehensive overview on the latest achievements in the area of thin film monitoring.

[How to get there]

**Laser Zentrum Hannover e.V. (LZH),
Hollerithallee 8, 30419 Hannover**



[Organizer]

PhotonicNet GmbH

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[in cooperation with]

Laser Zentrum Hannover e.V.

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Photonic-Net

Innovationsnetz Optische Technologien

IN COOPERATION WITH



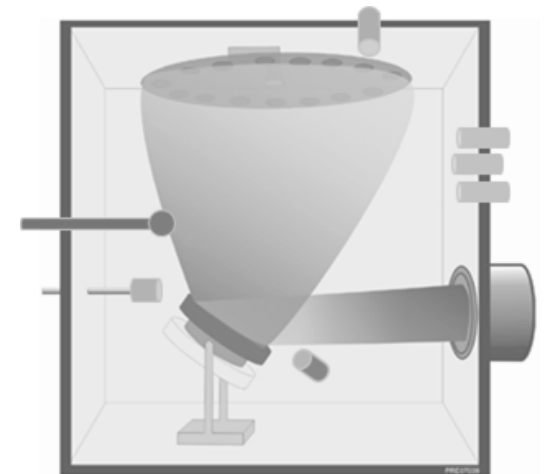
**Research Center
for Surface Technology**



LASER ZENTRUM HANNOVER e.V.

Monitoring in Thin Film Production

[Hanover, Germany
February 20th, 2018]





Hanover

February 20th, 2018



[Agenda]

Welcome **09.30**
 Detlev Ristau
 Laser Zentrum Hannover e.V., Hanover, Germany

Session I: Fundamentals

**Monitoring and Control of
Optical Deposition Processes** **09.40**
 Henrik Ehlers
 Laser Zentrum Hannover e.V., Hanover, Germany

Design and Optical Monitoring **10.10**
 Alexander Tikhonravov
 Lomonossov University, Moscow, Russia

**Optical Monitoring in Modern
Deposition Processes** **10.40**
 Detlef Arhilger
 Bühler Group, Leybold Optics, Alzenau, Germany

Coffee break, photograph **11.10**

Session II: Applications

Filter Systems **11.30**
 Marc Lappschies
 Optic Balzers Jena GmbH, Jena, Germany

**Optical Monitoring of beamsplitters and
antireflective coatings** **12.00**
 Dirk Isfort
 Carl Zeiss GmbH, Oberkochen, Germany

Optical Monitoring in IBS **12.30**
 Kai Starke
 CEC Cutting Edge Coatings GmbH,
 Hanover, Germany

Lunch break **12.40**

Session III: Applications

Chirped Mirrors **14.00**
 Vladimir Pervak
 Ludwig-Maximilians-University, Munich, Germany

**Prospects for the enhancement
of PIAD processes by monitoring of optical
thickness and plasma parameters** **14.30**
 Jens Harhausen
 Leibniz-Institute for Plasma Science and Technology,
 INP Greifswald, Germany

Coffee break **15.00**

Session IV: Advanced Monitoring Concepts

Optical Monitoring: New Approaches **15.30**
 Sebastian Schlichting
 Laser Zentrum Hannover e.V., Hanover, Germany

**Automatic generation of
monochromatic monitoring spreadsheets** **16.00**
 Tatiana Amotchkina,
 Ludwig-Maximilians-University, Munich, Germany

Final remarks **16.30**

Lab Tour LZH e.V. **16.40**

End **18.00**

[Registration]

Binding Registration
 Please register until **February 09th, 2018** at the latest

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or **ONLINE**

E-Mail: veranstaltung@photonet.de

I will attend the workshop

 Name

 Company / Institution

 Address

 Postal Code, City

 Phone No.

 E-Mail

 Member of competence network OT

 Date / Signature

Venue:
 Laser Zentrum Hannover e.V.
 Hollerithallee 8
 30419 Hannover
 Germany

PARTICIPATION FEE (plus VAT 19%):

290,00 € per person
 230,00 € per person for Members of competence
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